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Bib Data Sheet

CONFIRMATION NO. 6404

<b>SERIAL NUMBER</b> 09/901,038	<b>FILING DATE</b> 07/10/2001 <b>RULE</b>	<b>CLASS</b> 438	<b>GROUP ART UNIT</b> 1765	<b>ATTORNEY DOCKET NO.</b> 50090-301
<b>APPLICANTS</b> Toshihiro Yamashita, Tokyo, JAPAN; Hirotoishi Ise, Tokyo, JAPAN;				
<b>** CONTINUING DATA *****</b> <i>42</i>				
<b>** FOREIGN APPLICATIONS *****</b> JAPAN 2000-403083 12/28/2000 <i>42</i>				
<b>IF REQUIRED, FOREIGN FILING LICENSE GRANTED</b> <b>** 08/23/2001</b>				
Foreign Priority claimed <input checked="" type="checkbox"/> yes <input type="checkbox"/> no 35 USC 119 (a-d) conditions met <input checked="" type="checkbox"/> yes <input type="checkbox"/> no <input type="checkbox"/> Met after Allowance <i>42</i>		<b>STATE OR COUNTRY</b> JAPAN	<b>SHEETS DRAWING</b> 3	<b>TOTAL CLAIMS</b> 18
Verified and Acknowledged Examiner's Signature _____ Initials _____		<b>INDEPENDENT CLAIMS</b> 2		
<b>ADDRESS</b> McDermott, Will & Emery 600 13th Street, N.W. Washington, DC 20005-3096				
<b>TITLE</b> Plasma processing system in which wafer is retained by electrostatic chuck, plasma processing method and method of manufacturing semiconductor device				
<b>FILING FEE RECEIVED</b> 710	FEES: Authority has been given in Paper No. _____ to charge/credit DEPOSIT ACCOUNT No. _____ for following:		<input type="checkbox"/> All Fees <input type="checkbox"/> 1.16 Fees ( Filing ) <input type="checkbox"/> 1.17 Fees ( Processing Ext. of time ) <input type="checkbox"/> 1.18 Fees ( Issue ) <input type="checkbox"/> Other _____ <input type="checkbox"/> Credit	

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